

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:) Confirmation No.: 2015
Koichiro TANAKA et al.) Examiner: Abdulfattah Mustapha
Serial No. 10/582,614) Group Art Unit: 2812
Filed: June 12, 2006)
For: LASER IRRADIATION METHOD,)
LASER IRRADIATION APPARATUS,)
AND METHOD FOR)
MANUFACTURING)
SEMICONDUCTOR DEVICE)

AMENDMENT

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.